

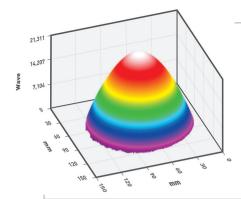


# Interferometric solution for filters and coated optics testing at dedicated wavelengths

PHASICS is innovating in optical metrology with a new instrument able to measure both transmitted and reflected wavefront error (TWE/ RWE). Coated and uncoated optics can be qualified over a diameter of 5.1 inches (130 mm) at their working wavelengths.

**Kaleo MultiWAVE** is an advantageous alternative and costeffective solution to the purchase of several interferometers. The system offers a **measurement accuracy comparable to Fizeau interferometry.** 

**Kaleo MultiWAVE** works at different wavelengths to perform qualification of optics and coatings at their working wavelengths.



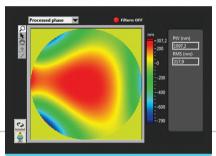
#### HIGH DYNAMIC RANGE

MEASUREMENT OF LARGE ABERRATIONS

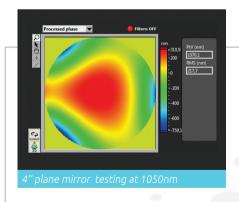
- More than 20λ of aberration can be measured with Kaleo MultiWAVE
- More dynamic range than a classical Fizeau interferometer

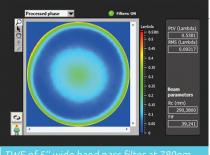
#### **APPLICATIONS**

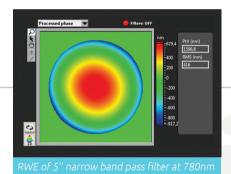
- Coated optics and filters testing at real operating wavelengths
- High dynamics surface testing











### **ACHROMATIC SYSTEM**

Same results at any wavelength

The instrument can be used at any wavelength to match the sample's operating wavelength

#### **KEY FEATURES**







High dynamic range



WFE & MTF measurement



Insensitive to vibration



Compatible with MetroPro & ISO

SYSTEM		
Configuration	Double pass	
Measurement capability	RWE of reflective surfaces TWE of transparent optics	
Number of wavelengths per instrument	1 or 2 (standard), up to 8 (custom)	
Custom wavelengths	Any wavelength from 193 nm to 14µm inculding: UV: 266, 355, 405 nm VIS/NIR: 550, 625, 780, 940, 1050 nm SWIR/MWR/LWIR: 1.55, 2.0, 3.39, 10.6 µm	
Clear aperture	5.1" (130 mm)	
Beam height	108 mm	
Alignment system	Live phase & Zernike cofficients display	
Polarization	Compatible with depolarizing optics	
Alignment FOV	+/- 2°	
Pupil focus range	+/- 2.5 m	
Dimension/Weight	910x600x260 mm³ , 25 kg	
Vibration isolation	Not necessary	

PERFORMANCES(1)			
RMS repeatability (2)	<0.7 nm (< λ /900)		
Accuracy	80 nm PV (3)		
Dynamic range (defocus)	500 fringes (SFE=150 μm)		
Sample reflectivity range	~4% - 100%		

<sup>(1)</sup> On a 4" pupil size, with a 625 nm source

#### **MARKETS**







Space & Defense



Automotive

<sup>(2) 36</sup> sequential measurements are performed on a 4" reference mirror, each being averaged 16 times. A reference is defined as the average of all odd numbered measurements. RMS repeatability is then defined as the average RMS difference plus 2 times the standard deviation of the difference between even numbered measurements and the reference.

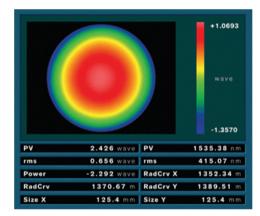
<sup>(3)</sup> For a 1  $\mu$ m PV defocus.

124.9 mm

#### **FIZEAU INTERFEROMETER**

## PV 2.367 wave PV 1498.13 nm rms 0.637 wave rms 403.26 nm Power -2.213 wave RadCrv X 1367.01 m

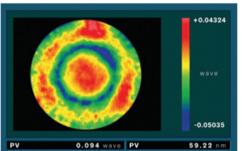
#### **KALEO MULTIWAVE**



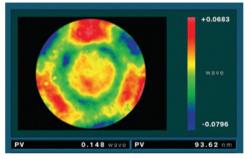


Size X

RAW MEASUREMENT



124.9 mm | Size Y



NBP-780nm - The difference between the 2 measurements on the same pupil is below 40

		FIZEAU	PHASICS
Diameter (mm)		124.9	125.4
RWE (nm PtV)		1498.13	1535.38
RWE (nm RMS) without PST/TLT/PWR		35.2	28.1
RWE (nm RMS) without ST/TLT/PWR/AST/CMA/SA		9.1	12.9
ISO 10110	SAG (fr)	5.13	5.04
	IRR (fr)	0.75	0.61
	RSI (fr)	0.34	0.23
	RMSt (fr)	1.477	1.459
	RMSi (fr)	0.129	0.103
	RMSa (fr)	0.085	0.059

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